

**ELEX ESE Regular (VIII<sup>th</sup> Sem/ CBCGS-H) October 2020**  
**Microelectromechanical Systems(MEMS) Technology**  
**SEM VIII(CBCGS-H)**  
**SAMPLE QUESTION SET for MEMS Technology**

**Note:** MCQ comprises of 1 marks and 2 marks questions

1. \_\_\_\_\_ is the unintentional adhesion of microstructural structures with a large surface-area-to-volume ratio when restoring forces are not able to overcome the interfacial forces such as capillary, electrostatic, van der Waals, and residual stress.

- a. Creep
- b. Stiction
- c. Friction
- d. Actuation

2. \_\_\_\_\_ defined as a change in electrical resistance of solids when subjected to stress fields.

- a. Piezoelectric
- b. Photoresist
- c. Piezoresistance
- d. none

3. \_\_\_\_\_ defines the change in resistance as a function of the ambient temperature.

- a. TCR
- b. Piezoresistance
- c. Thermal resistance
- d. None

4. \_\_\_\_\_ is the change in the electrical resistivity of a solid induced by an applied mechanical stress.

- a. Piezoresistance
- b. Electromechanical stress
- c. TCR
- d. stiffness

5. In the \_\_\_\_\_, a change in the cantilever's z-displacement indicates a change in load or intrinsic stress.

- a. Dynamic mode
- b. Static mode
- c. Pseudo static
- d. Pseudo Dynamic

6. In which cantilever mode, it takes benefit of the bimetallic effect that leads to a bending of a bimaterial micro cantilever with change in temperature.

- a) Static mode
- b) Dynamic mode
- c) Heat mode
- d) None

7. Hall effect sensors are an application of \_\_\_\_\_ law.

- a. Ampere's
- b. Gauss's
- c. Lorentz's
- d. Lenz's

8. The following are /is Characteristics of a mechanical (micro.actuator)

- a. Stroke
- b. Force/torque
- c. Stiffness
- d. Hysteresis

9. The wet etching process is \_\_\_\_\_

- a. isotropic
- b. anisotropic
- c. isotropic for few materials
- d. isobaric process

10. Following acts as detector in Optical sensor

- a Light emitting diode
- b Photo diode
- c Transistor
- d All of the above

11. First material known to be used by man

- a Cotton
- b Bronze
- c Iron
- d Rock

12. First metal known to be used by man

- a Iron
- b Bronze
- c Silver
- d Aluminium

13. Which one of the following is not basic component of Materials Science?

- a Cost
- b Properties

- c Structure
- d Performance

14. Figure out the odd statement about ceramics in the following

- a Good insulators of heat and electricity
- b Usually less dense than metals
- c Ductile in nature
- d Contains both metallic and nonmetallic elements

15. Pick the composite from the list

- a Wood
- b Steel
- c Nylon
- d Mica

16. Not an example for actuator

- a Optical fiber
- b Shape memory alloys
- c Magneto-strictive materials
- d Electro-/Magneto-rheological fluids

17. Strong and ductile materials

- a Polymers
- b Ceramics
- c Metals
- d Semiconductors

18. Presently most used metal in the world

- a Aluminium
- b Gold
- c Steel
- d Silver

19. Detrimental property of a material for shock load applications

- a High density
- b Low toughness
- c High strength
- d Low hardness

20. Democratic material

- a Diamond
- b Titanium
- c Iron
- d Gold

21. Which of the following software can be used to make a schematic design of your microfabricated sensor?

- a SolidWorks
- b PSpice
- c ProE
- d MATLAB

22. Change in output of any sensor with respect to change in input is expressed as
- Specificity
  - Sensitivity
  - © Threshold limit
  - Gauge Factor
23. Lithography process is used to pattern:
- Metal and semiconductor layers
  - Metal and insulating layers
  - © Semiconductor and insulation layers
  - Metal, Semiconductor and insulation layers
24. Smallest change in input which a sensor can detect and express as output:
- Precision
  - Cut-in-voltage
  - © Resolution
  - Threshold
25. The following main dynamic characteristic(s) is usually considered in Mechatronics application of sensors.
- Response time
  - Rise time
  - Time constant
  - All of the above
26. The following is (are) type(s) of Hall Effect sensors.
- Linear Hall Effect sensor
  - Threshold Hall Effect sensor
  - Both a and b
  - None of the above
27. Following is (are) true for Hall Effect sensors.
- They can operate as switches of high frequency
  - They cost less than electromechanical switches
  - They are free from contact bounce problem
  - All of the above
- 28- A piezo-electrical crystal generates voltage when subjected to \_\_\_\_ force.
- Electrical
  - Mechanical
  - Gravity
  - All of the above
- 29-Hall Effect sensors are used in
- Flow meter
  - Fuel level indicator
  - Both a and b
  - None of the above
- 30-Any radiation of appropriate wavelength fall on the depletion layer of p-n junction develops a potential difference between the junction' is working principle of
- Hall Effect sensor
  - Proximity sensor
  - Light sensor

d All of the above

31-Following type of sensors are used to generate information in object grasping and obstacle avoidance.

- a Hall Effect sensor
- b Proximity sensor
- c Light sensor
- d Optical sensors

32-Inductive ----- sensors can be effective only when the objects are of \_\_\_\_\_ materials.

- a proximity, Ferro magnetic
- b piezo,Diamagnetic
- c proximity,Paramagnetic
- d proximity ,nonmagnetic

33. Why micro-heater is fabricated in drug screening device?

- a. At elevated temperature sensitivity increases
- b.To maintain normal human body temperature on the chip
- c. Matrigel is stable only at elevated temperature (~ 320K.)
- d. cost consideration

34. The following are /is Characteristics of a mechanical (micro.actuator

- a Stroke
- b Force/torque
- © Stiffness
- d Hysteresis

35-A beam is a structural member which is subjected to

- a Axial tension or compression
- b Transverse loads and couples
- © Twisting moment
- d.No load, but its axis should be horizontal and x-section rectangular or circular

36-Which of the following is not covered under Mechanical energy domain?

- a Distance
- b Latent heat
- c Force
- d Size

37-Which of the following form the basis of Electrical domain?

- a Current
- b Resistance
- c Inductance
- d All of the above

38-The sensors are classified on the basis of

- a Functions
- b Performance
- c Output
- d All of the above

39-The following is not a static performance parameter to be looked into before selecting a parameter.

- a Range
- b Deflection

- c Stability
- d Error

40-The following main dynamic characteristic(s) is usually considered in Mechatronics application of sensors.

- a Response time
- b Rise time
- c Time constant
- d All of the above

41-The ability to give same output reading when same input value is applied repeatedly is known as

- a Stability
- b Repeatability
- c Accuracy
- d Sensitivity

42-It is the ability of the sensor to indicate the same output over a period of time for a constant input.

- a Stability
- b Resolution
- c Error
- d Impedance

43-It is the time required to come to an output value within the specified error level.

- a Response time
- b Rise time
- c Settling time
- d None of the above

44-Following is the coded output.

- a Modulation of amplitude
- b Modulation of frequency
- c Modulation of pulse width
- d All of the above

45-Following is not an example of transducer.

- a Analogue voltmeter
- b Thermocouple
- c Photo electric cell
- d Pneumatic cylinder

46-A piezo-electrical crystal generates ----- when subjected to \_\_\_\_ force.

- a Voltage,Electrical
- b Voltage, Mechanical
- c Current,Gravity
- d Current, non electrical

47. Weibull distribution provides usable mathematical descriptions of..... rate:

- a. Reliability & Failure Rate
- b. Passing rate & Reliability
- c. Failure rate & Flat rate
- d. Reliability & Flat rate

48. ....of the beam is inversely proportional to the \_\_\_\_\_ of the beam.

- a. stiffness, Slope
- b. stress,Support reaction

- c. stiffness, Deflection
- d. length, Load

49. Dynamic deflection of the pulsed-voltage activated piezoelectric diaphragm can generate a pressure wave to eject the ink out of the nozzle

- a Deflection, piezoresistive
- b Refraction, piezoelectric
- c. deflection, piezoelectric
- d refraction, piezoelectric